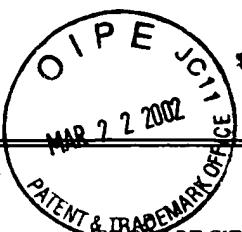


Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE			ATTY. DOCKET NO. MI22-1914	SERIAL NO. Priority 09/651,815	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)					APPLICANT Jerome Michael Eldridge		
					FILING DATE Priority August 30, 2000	GROUP Priority 2813	
U.S. PATENT DOCUMENTS							
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
<i>JM</i>	AA	3,954,523	05/76	Magdo et. al.			
<i>JM</i>	AB	5,023,200	06/91	Blewer et. al.			
<i>JM</i>	AC	5,470,801	11/95	Kapoor et. al.			
<i>JM</i>	AD	5,885,900	03/99	Schwartz			
<i>JM</i>	AE	5,731,241	03/98	Jang et. al.			
<i>JM</i>	AF	5,783,253	07/98	Roh			
<i>JM</i>	AG						
FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Subclass	Translation
	AB						Yes No
	AM						
	AN						
	AO						
	AP						
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
<i>JM</i>	AQ			Togo, M., "A Gate-side Air-gap Structure (GAS) to Reduce the Parasitic Capacitance in MOSFETs", 1996 Sympos. on VLSI Technology			
<i>JM</i>				Digest of Technical Papers, IEEE 1996, pp. 38-39			
<i>JM</i>	AR			Anand, M.B., "NURA: A Feasible, Gas-Dielectric Interconnect Process", 1996 Symposium on VLSI Technology Digest of Technical			
<i>JM</i>				Papers, IEEE 1996, pp. 82-83			
<i>JM</i>	AS			Watanabe, H., "A Novel Stacked Capacitor with Porous-Si Electrodes for High Density DRAMs", Microelectronics Research			
<i>JM</i>				Laboratories, NEC Corp., date unknown, pp. 17-18			
<i>JM</i>	AT			ABSTRACT: Anderson, R.C. et. al., "Porous Polycrystalline Silicon: A New Material For MEMS", Jnl. of Microelectromechanical			
<i>JM</i>				Systems (Mar. 1994), Vol. 3, No. 1, pp. 10-18			
<i>JM</i>	AU			M. B. Anand, "Use of Gas as Low-k Interlayer Dielectric in LSI's: Demonstration of Feasibility", IEEE Transactions On Electron			
<i>JM</i>				Devices, Vol. 44, No. 11, November 1997, pp. 1965-1971			
EXAMINER		<i>James Saito</i>			DATE CONSIDERED		<i>5/3/03</i>
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							

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					FILING DATE Priority August 30, 2000		GROUP Priority 2813		
U.S. PATENT DOCUMENTS									
*Examiner Initial		Document Number	Date	Name		Class	Subclass	Filing Date If Appropriate	
<i>Jde</i>	AA	U.S. Patent Application Serial No. 08/947,847		Juengling et al.				10/9/97	
	AB								
	AC								
	AD								
	AE								
	AF								
	AG								
FOREIGN PATENT DOCUMENTS									
		Document Number	Date	Country		Class	Subclass	Translation	
	AL							Yes	No
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OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)									
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	AU								
EXAMINER <i>Karen Salter</i>				DATE CONSIDERED <i>5/3/03</i>					
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				FILING DATE January 11, 2002	GROUP 2813		
U.S. PATENT DOCUMENTS							
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
<i>jk</i>	AA	5,273,616	12/1993	Bozler	156	603	
<i>jk</i>	AB	6,140,200	10/2000	Eldridge	438	396	
<i>jk</i>	AC	5,989,776	11/1999	Felter et al.	430	270	
	AD						
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FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Subclass	Translation
							Yes
	AM						No
	AN						
	AO						
	AP						
	AQ						
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
	AR						
	AS						
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EXAMINER	<i>haseena Schley</i>			DATE CONSIDERED	<i>5/3/03</i>		
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